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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re application of

: Mail Stop: ISSUE FEE

Shoriki NARITA et al.

: Confirmation No. 1853

Serial No. 10/019,700

: [Group Art Unit 2825]

Filed January 2, 2002

: Examiner Igwe U. Anya]

BUMP FORMING APPARATUS FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVAL METHOD  
FOR CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVING UNIT FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, AND CHARGE APPEARANCE  
SEMICONDUCTOR SUBSTRATE

**RESUBMISSION OF REFERENCES**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Applicants note that the Submission of References dated September 20, 2004 contained a typographical error. Specifically, the date of reference JP 2002009569 should be 01/2002 not 01/2001. Below is a corrected listing of the previously submitted references.

USP 6,198,616, 03/2001, Dahimene et al.  
JP 01077111, 03/1989 (Abstract)  
JP 2002009569, 01/2002 (Abstract)  
JP 2002203995, 07/2002 (Abstract)

Respectfully submitted,

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October 20, 2004

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